

**Notice of References Cited**

Application/Control No.

09/742,224

 Applicant(s)/Patent Under  
Reexamination  
FANG ET AL.

Examiner

Timothy R. Stampf

Art Unit

2857

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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	B	US-5,204,618	04-1993	Matsuoka	324/158.1
	C	US-5,030,905	07-1991	Figal	324/760
	D	US-5,798,653	08-1998	Leung, Jr.	324/760
	E	US-5,822,218	10-1998	Moosa et al.	716/4
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	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Chien et al., "A Nonparametric Approach to Estimating System Burn-in Time", IEEE Transactions on Semiconductor Manufacturing, Vol. 9, No. 3, August 1996, pages 461-467
	V	Chien et al., "Modeling & Maximizing Burn-in Effectiveness", IEEE Transactions on Reliability, Vol. 44, No. 1, March 1995, pages 19-25
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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